

## Dependence of the structural and the electrical properties on the Hg/Te flux-rate ratios for $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$ epilayers grown on CdTe buffer layers

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Potential applications of  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  thin films in optoelectronic devices in the area of the infrared detectors have driven an extensive and successful effort to grow the films on various semiconductor substrates [1–3]. The growth of *n*-type and *p*-type  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epitaxial films with interfacial abruptnesses on the scale of a few lattice constants has been particularly attractive because of many promising applications for infrared focal-plane array technologies [4, 5]. Even though liquid-phase epitaxy method have been used to grow extensively  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epitaxial films, the samples grown by those methods have intermixing problems at heterointerfaces. Since a molecular-beam epitaxy (MBE) growth method has overcome the inherent problems, high-quality  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epitaxial films can grown by using the MBE method [6, 7]. There has been considerable interest in the growth of CdTe buffer layers on GaAs substrates prior to the growth of  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epitaxial films since the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}/\text{GaAs}$  heterostructures have inherent problems for obtaining high-quality epitaxial layers due to their large lattice mismatch ( $\Delta a/a = 14.6$ ) [8]. Since the physical properties of the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  films significantly affect the fabrication of high-efficiency optoelectronic devices, studies of the structural and the electrical properties of the films are necessary for achieving high-performance devices.

This letter reports the dependence of the structural and the electrical properties on the Hg/Te flux-rate ratios for  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  thin films grown on CdTe buffer layers by using MBE. Scanning electron microscopy (SEM) measurements were taken to characterize the surface qualities of the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  layers, and double crystal X-ray rocking curve (DCRC) measurements were performed to investigate their structural qualities. Hall-effect measurements were carried out to determine the carrier concentrations and the mobilities of the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epilayers.

The samples used in this study were grown on semi-insulating GaAs (211) B substrates. The GaAs substrates were degreased in warm trichloroethylene (TCE), rinsed in deionized water thoroughly, etched in a mixture of  $\text{H}_2\text{SO}_4$ ,  $\text{H}_2\text{O}_2$ , and  $\text{H}_2\text{O}$  (5:1:1) at 40 °C for 60 s, and rinsed in TCE again. After the wafers

were dried by a  $\text{N}_2$  gas, they were mounted onto a molybdenum susceptor. After the GaAs substrates were thermally cleaned at 300 °C for 3 h in the introduction chamber, they were transferred into the growth chamber. Before  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  growth, the GaAs substrates were thermally cleaned at 580 °C for 15 min in a  $\text{Te}_2$  atmosphere to remove the oxide layers existing on the substrates. The deposition of the CdTe buffer layer was performed at a substrate temperature of 310 °C by using CdTe and Te effusion cells, the typical growth rate was approximately 0.6  $\mu\text{m}/\text{h}$ . The typical thickness of the CdTe buffer layer was approximately 7  $\mu\text{m}$ , and the CdTe buffer layer was employed to reduce the strain effect in the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  layer due to the lattice mismatch between the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  layer and the GaAs substrate. The  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epilayers were grown on the CdTe buffer layer at 195 °C by using CdTe, Te, and Hg cells. The growth rate of the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  thin film was approximately 3  $\mu\text{m}/\text{h}$ , and the typical thickness of the film was about 12  $\mu\text{m}$ . The flux-rate ratios of Hg/Te were 80, 85, 90, 95, 100, 120, and 150. Hall-effect measurements were performed in the temperature of 77 K in a magnetic field of 3200 G in a magnet system using a Keithley 181 nanovoltmeter.

Fig. 1 shows SEM images of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers grown on CdTe buffer layers at Hg/Te flux-rate ratios of (a) 80, (b) 85, (c) 90, (d) 100, (e) 120, and (f) 150. When the Hg/Te flux-rate ratio is 80, the high-density defects with a size of about 30  $\mu\text{m}$  appear in the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers, as shown in Fig. 1a. When the Hg/Te flux-rate ratio is 85, the larger sizes of void defects similar to the Fig. 1a appear in the surface of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayer, as shown in Fig. 1b, and the existence of the defects is caused by the Hg deficiencies [9, 10]. When the Hg/Te flux-rate ratio is 90, another type of the defect different from the void defect appears in the surface of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayer. When the Hg/Te flux-rate ratio is 100, the surface of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  (211) B epilayer is mirrorlike without any indication of microcracks and defects, as shown in Fig. 1d. When the Hg/Te flux-rate ratios are 120 and 150, the honeycomb patterns appear at the surface of the  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  epilayer due to the Hg oversupply, as

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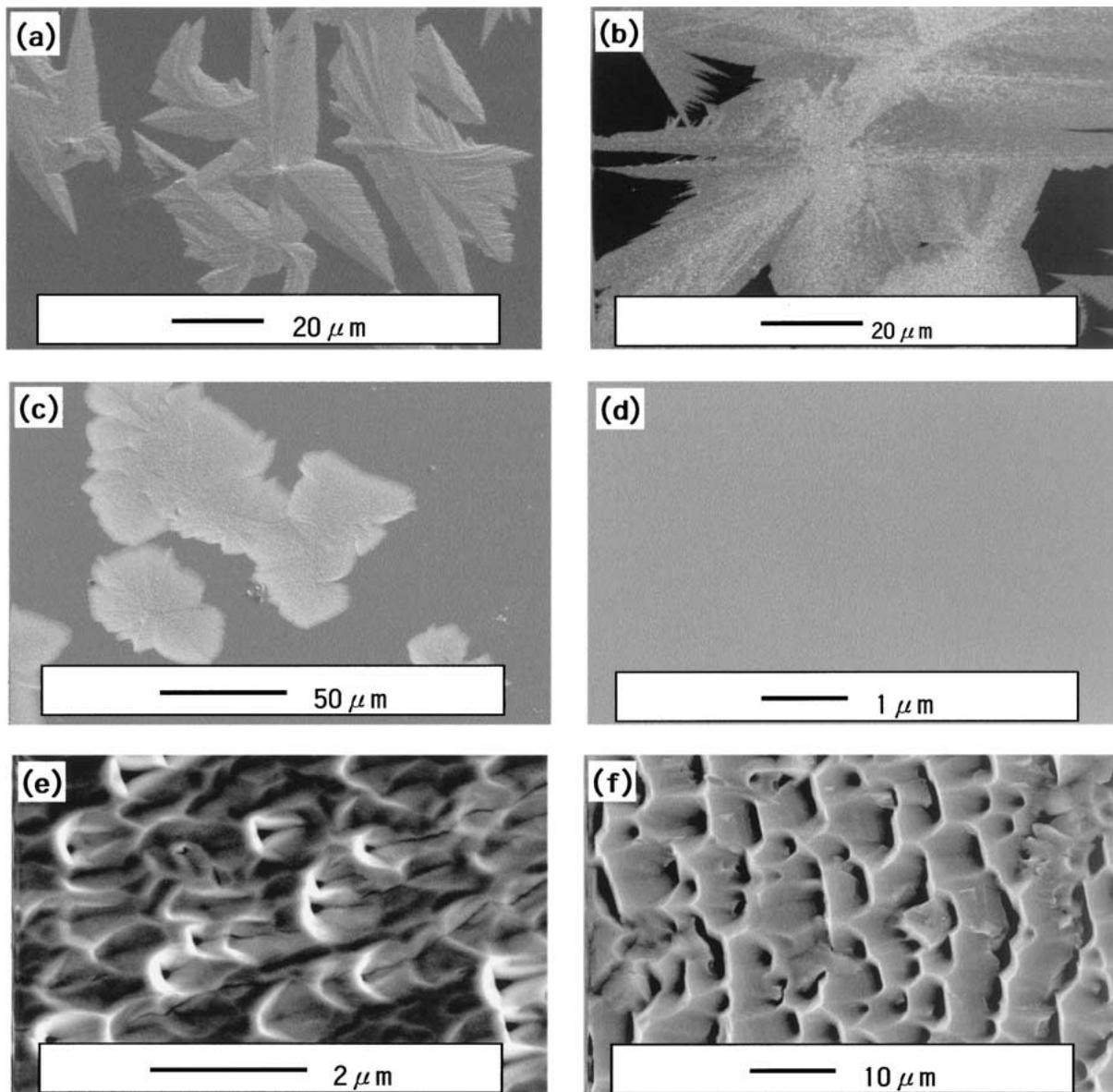


Figure 1 Scanning electron microscopy images of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers grown on CdTe buffer layers at Hg/Te flux-rate ratios of (a) 80, (b) 85, (c) 90, (d) 100, (e) 120, and (f) 150.

shown in Fig. 1e and f. Since the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epitaxial film grown at an Hg/Te flux-rate ratio of 100 has the best surface morphology among the several samples grown at various Hg/Te flux-rate ratios, and the optimum amount of the Hg/Te flux-rate ratio for the growth of the high-quality  $\text{Hg}_{1-x}\text{Cd}_x\text{Te}$  thin film is 100.

Fig. 2 shows the full width at half maximum (FWHM) as a function of the Hg/Te flux-rate ratio of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers obtained from the DCXRC measurements. The FWHM of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers decreases with increasing the Hg/Te flux-rate ratio. When the Hg/Te flux-rate ratio is 100, the minimum value of the FWHM of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers is as small as 160 arcsec, as shown in Fig. 2. When the Hg/Te flux-rate ratio is above 100, the values of the FWHM of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers increases due to the deterioration of the quality of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayer resulting from the Hg oversupply.

Fig. 3 shows carrier concentrations as a function of the Hg/Te flux—rate ratio of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers determined from the Hall effect measurements at 77 K, and mobilities as a function of the Hg/Te flux—

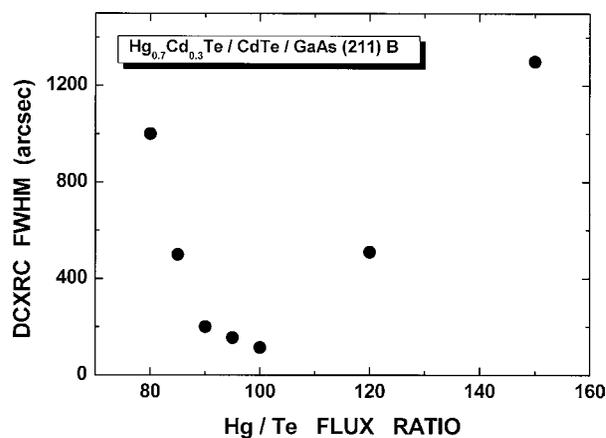


Figure 2 Full width at half maxima as a function of the Hg/Te flux-rate ratio of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers determined from the double crystal X-ray rocking curve measurements.

rate ratio of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayers are shown in Fig. 4. When the Hg/Te flux-rate ratio is 100, the values of the carrier concentration and the mobility of the  $\text{Hg}_{0.7}\text{Cd}_{0.3}\text{Te}$  epilayer are minimum and maximum,

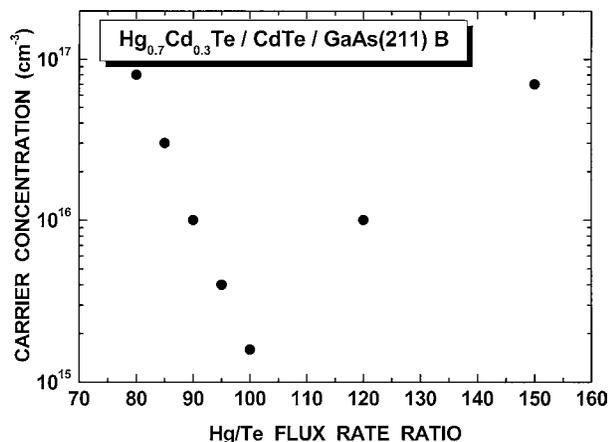


Figure 3 Carrier concentrations as a function of the Hg/Te flux-rate ratio of the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayers determined from the Hall effect measurements at 77 K.

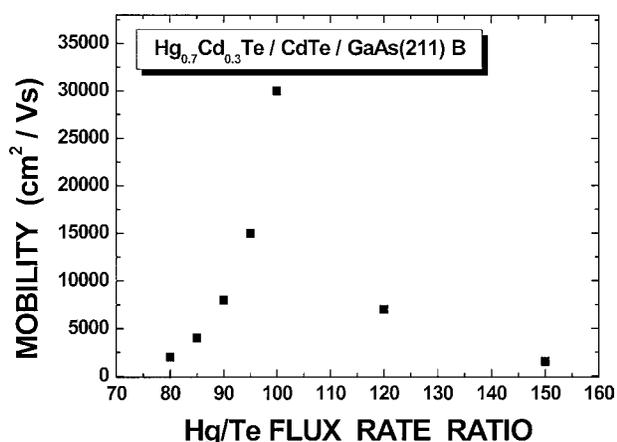


Figure 4 Mobilities as a function of the Hg/Te flux-rate ratio of the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayers determined from the Hall effect measurements at 77 K.

respectively. When the Hg/Te flux-rate ratio is 100, the value of the carrier concentration is  $2 \times 10^{15} \text{ cm}^{-3}$ , and the corresponding mobility is  $30000 \text{ cm}^2/\text{Vs}$ . These results are in reasonable agreement with the surface and the structural properties obtained by the SEM and DCRC measurements. Therefore, the optimum condition of the Hg/Te flux-rate ratio for the surface, structural, and electrical properties of the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayers is 100.

In summary, the results of SEM and DCRC measurements showed that the surface and structural properties of the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayers grown on the CdTe buffer layers at a Hg/Te flux-rate ratio of 100 had the best quality. When the Hg/Te flux-rate ratio is 100, the values of the carrier concentration and the mobility of the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayer are minimum and maximum, respectively. These results indicate that the Hg<sub>0.7</sub>Cd<sub>0.3</sub>Te epilayers grown on the CdTe buffers at a Hg/Te flux-rate ratio of 100 hold promise for application in optoelectronic devices.

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### References

1. J. P. FAURIE and A. MILLION, *J. Cryst. Growth* **54** (1981) 582.
2. M. BOUKERCHE, J. RENO, I. K. SOU, C. HSU and J. P. RAURIE, *Appl. Phys. Lett.* **48** (1986) 1733.
3. T. SKAULI, H. STEEN, T. COLIN, P. HELGESEN, S. LOVOLD, C. T. ELLIOTT, N. T. GORDON, T. J. PHILLIPS and A. M. WHITE, *ibid.* **68** (1996) 1235.
4. M. BOUKERCHE, R. RENO, I. K. SOU, C. HSU and J. P. FAURIE, *ibid.* **48** (1986) 1733.
5. J. S. GOUGH, M. R. HOULTON, S. J. C. IRVINE, N. SHAW, M. L. YOUNG and M. G. ASTLES, *J. Vac. Sci. Technol. B* **9** (1991) 1687.
6. P. S. WIJEWARNASURIYA and S. SIVANANTHAN, *Appl. Phys. Lett.* **72** (1998) 1694.
7. M. S. HAN, T. W. KANG and T. W. KIM, *J. Mater. Res.* **14** (1999) 2778.
8. S. RUJIRAWAT, L. A. ALMEIDA, Y. P. CHEN and S. SIVANANTHAN, *Appl. Phys. Lett.* **71** (1997) 1810.
9. L. H. JHANG and C. J. SUMMERS, *J. Electron. Mater.* **27** (1998) 634.
10. L. HE, Y. WU, L. CHEN, S. L. WANG, M. F. YU, Y. M. QIAO, J. R. YANG, Y. J. LI, R. J. DING and Q. Y. ZHANG, *J. Cryst. Growth* **227/228** (2001) 677.

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